

<b>Notice of References Cited</b>	Application/Control No. 10/695,439		Applicant(s)/Patent Under Reexamination SAKAI ET AL.	
	Examiner Howard Weiss		Art Unit 2814	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,943,376	09-2005	Nakatsuka et al.	257/77
	B	US-			
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	D	US-			
	E	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

#### FOREIGN PATENT DOCUMENTS

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#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Tsukimoto, S., et al., "Electrical properties and microstructure of ternary Ge/Ti/Al ohmic contacts to p-type 4H-SiC", Nov., 2004, J. App. Phys., Vol. 96, No. 9, p. 4976-81
	V	Konishi, R., et al., "Development of Ni/Al and Ni/Ti/Al ohmic contact materials for p-type 4H-SiC", 2003, Mat. Sci. Eng., B98, p.286-93
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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